



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Pan et al.

Serial No.: 09/614,113

Filed: July 12, 2000

For: TECHNIQUE FOR ELIMINATION OF PITTING ON SILICON SUBSTRATE DURING GATE STACK ETCH

Examiner: C. Brown

Group Art Unit: 1765

Attorney Docket No.: 2915.3US

(96-0149.2)

CERTIFICATE OF MAILING

I hereby certify that this correspondence along with any attachments referred to or identified as being attached or enclosed is being deposited with the United States Postal Service as First Class Mail (under 37 C.F.R. § 1.8(a)) on the date of deposit shown below with sufficient postage and in an envelope addressed to the Commissioner for Patents, Washington, D.C. 20231.

August 22, 2001 Date of Deposit

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Devin R. Jensen
Typed/printed name of person whose signature is contained above

RESPONSE TO RESTRICTION REQUIREMENT

Box Non-Fee Amendment Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Applicants herein acknowledge the restriction requirement in the above-referenced application. Applicants hereby elect the claims of Group II, claims 3 through 18, without traverse.

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Application Serial No. 09/614,113

An early Office Action on the merits is respectfully solicited.

Respectfully submitted,

Devin R. Jensen

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Date: August 22, 2001

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